

APD.Detectors Workshop

ESRF, Grenoble, France

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*Si-APD Detectors
for Nuclear Excitation Experiments*

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Outline

1. Nuclear excitation experiments using SR-X-rays and Si-APD
2. Hamamatsu Photonics's Si-APDs for NRS
3. Nuclear excitation by electron transition (NEET) and a Si-Avalanche Diode for electron detection
4. For Future
5. Conclusions

1. Nuclear excitation experiments using synchrotron X-rays

Ex..Nuclear resonance of ^{57}Fe : 14.4keV, $T_{1/2}=98\text{ns}$

We need an X-ray detector with a nanosecond time-resolution to record a time spectrum !

At a single or several-bunch mode operation,

Prompt radiation by electronic scattering

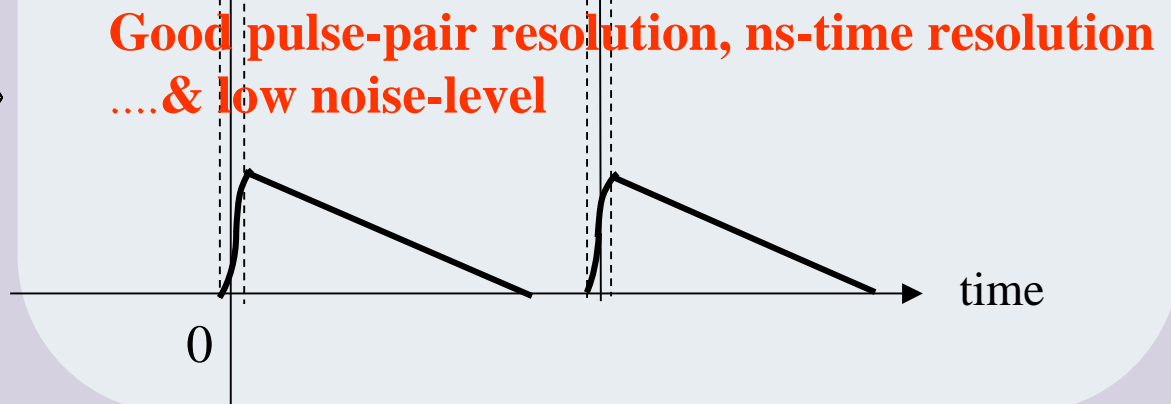
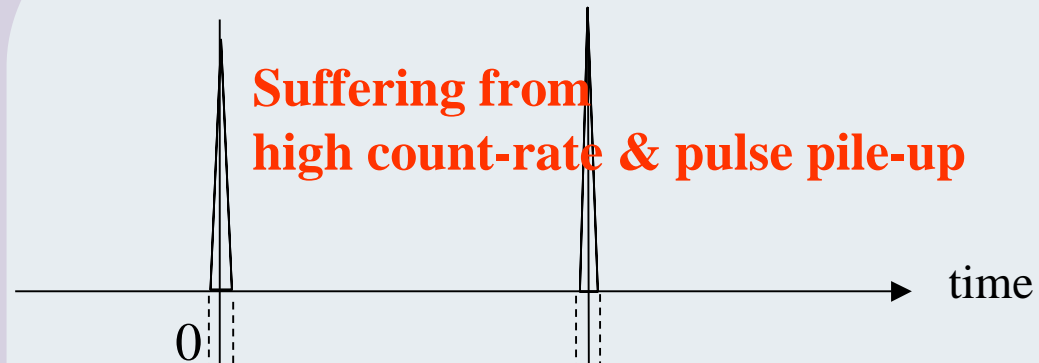
Intense!
: $\geq \text{MHz}$

Radiation emitted from nuclei

Weak !
: $\sim 1\text{Hz}$



Detector output counts

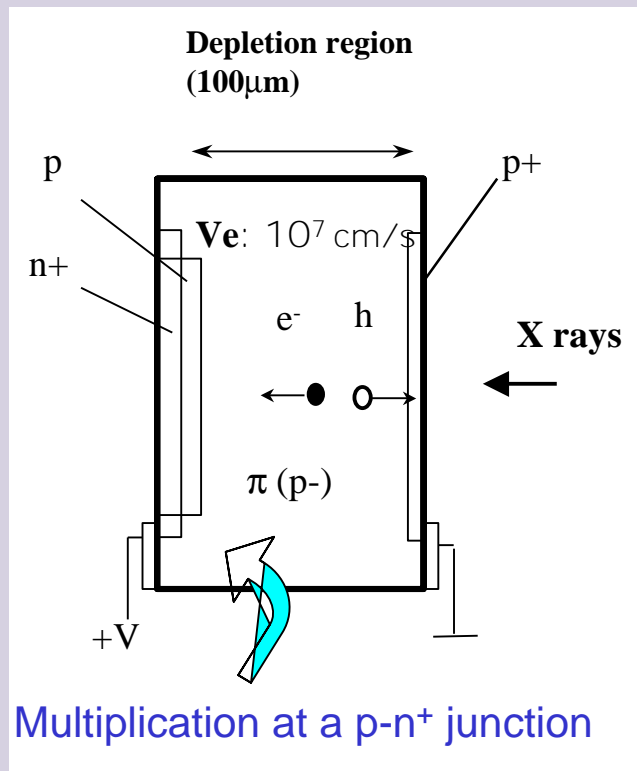


A silicon avalanche photodiode

Our detectors:

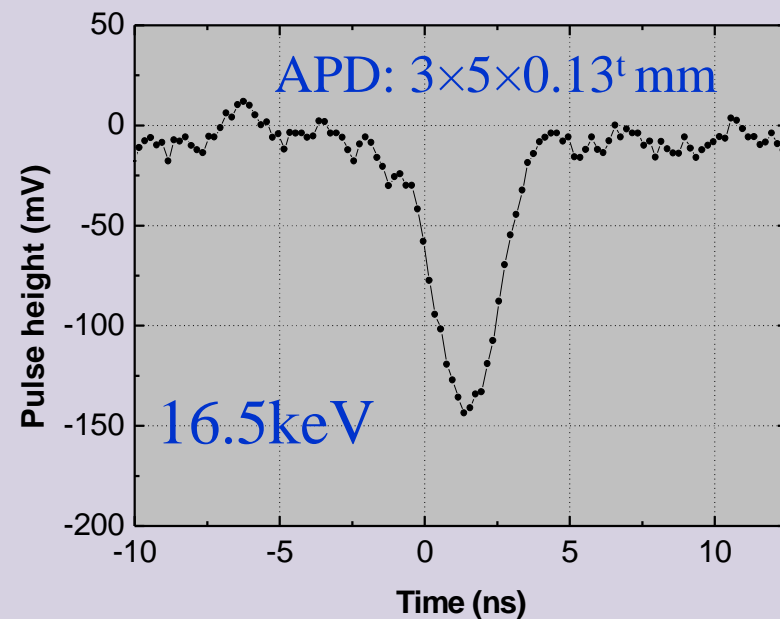
Detecting radiation **Without a scintillator** to obtain a faster response

⇒ By processing signals With a wide-band amplifier (gain > 100),
a nanosecond-width pulse for one X-ray photon



Ex. C30872E (EG&G Opt.)
Reach-through, bulk

high-rate capacity : up to 10^8 s^{-1}
time resolution : < 50ps – 1.5ns
Noise.level : 10^{-2} s^{-1} (one device)



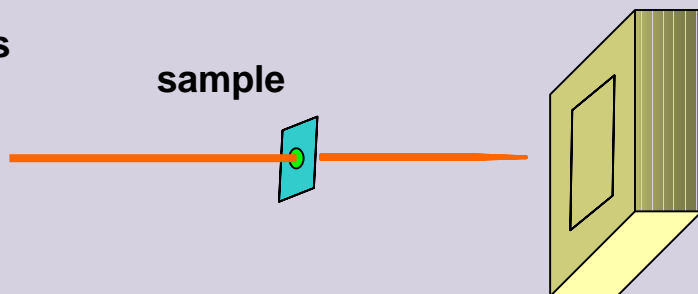
Si-APD detectors for Nuclear Resonant Scattering

In Photon Factory NE3A, SPring-8 BL09XU

Mössbauer time spectroscopy using time structure by the interference of hyperfine transitions

X-rays

sample

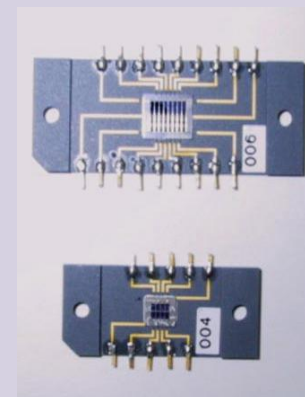


A stack of Si-APD plates
& An array detector

3mm in dia. 4ch,
150 μ m, $\epsilon \approx 80\%$.



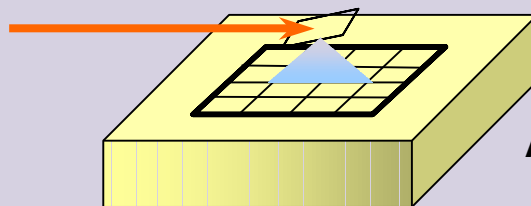
0.5x2mmx(8x2)ch,
0.5x1mmx(4x2)ch,
50 μ m.(monolithic)



Phonon energy spectroscopy using a neV resolution

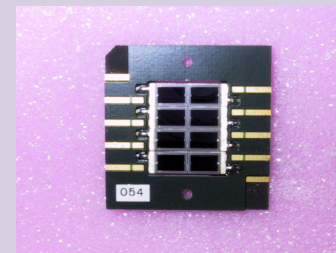
X-rays

sample



Array detector

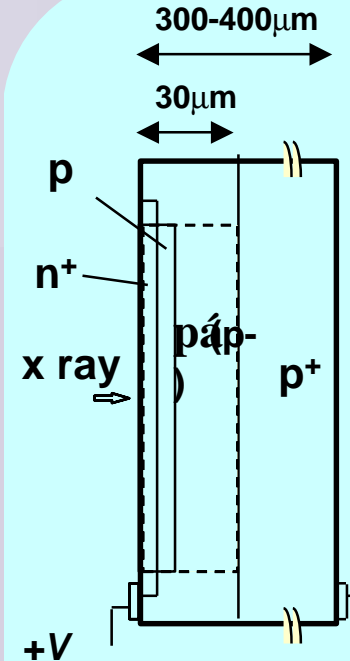
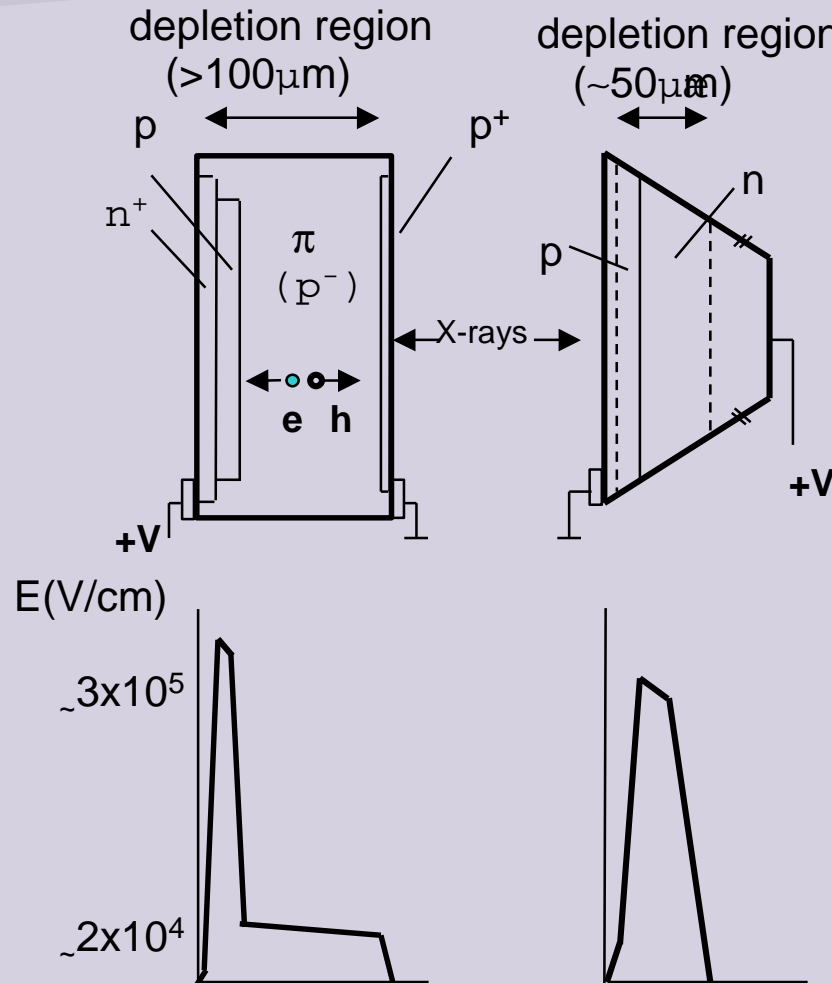
3x5mmx(4x2)ch,.150 μ m



2. Hamamatsu's Si-APDs for NRS

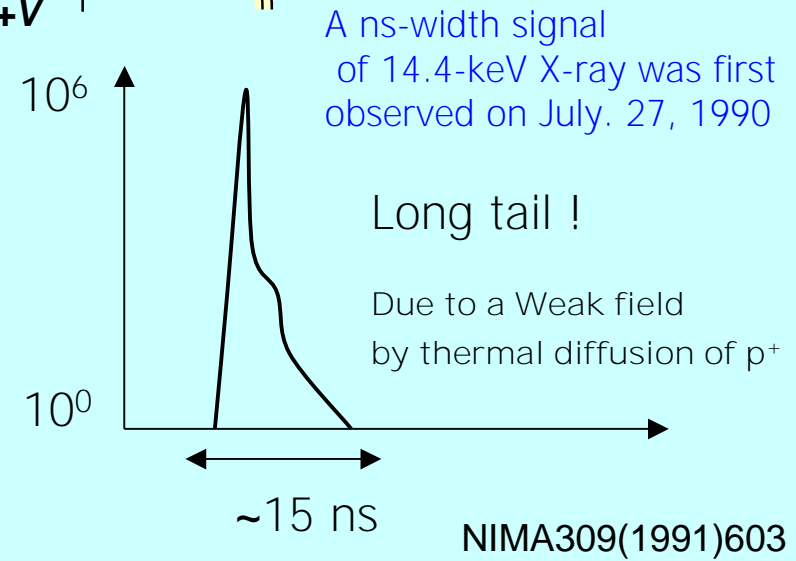
Type of Si-APDs

(a) reach-through (b) beveled edge



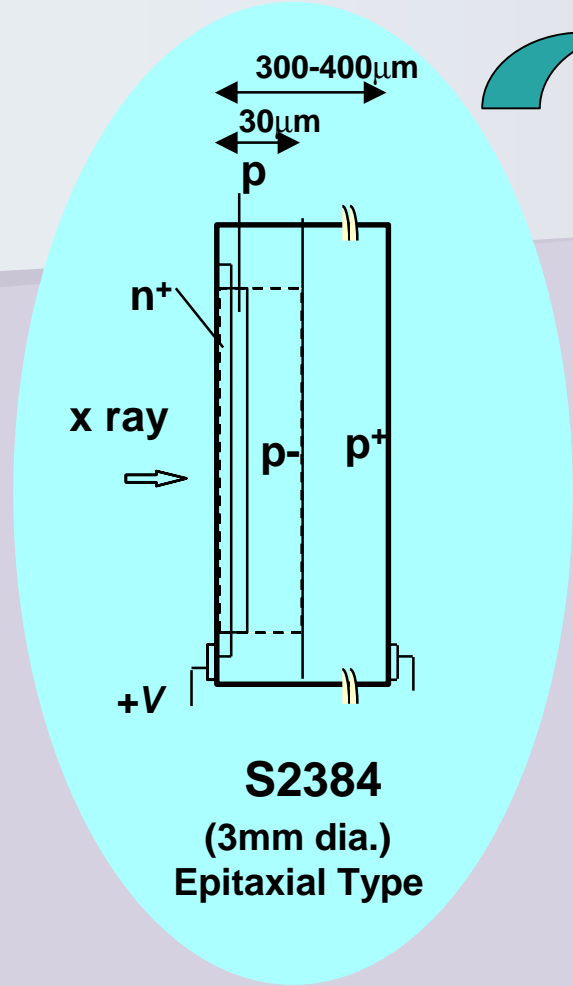
Hamamatsu :
S2384 (3mm dia.)
 Commercial, IR sensor

Reach-through type
 (epitaxial growth)



We had to improve the device !

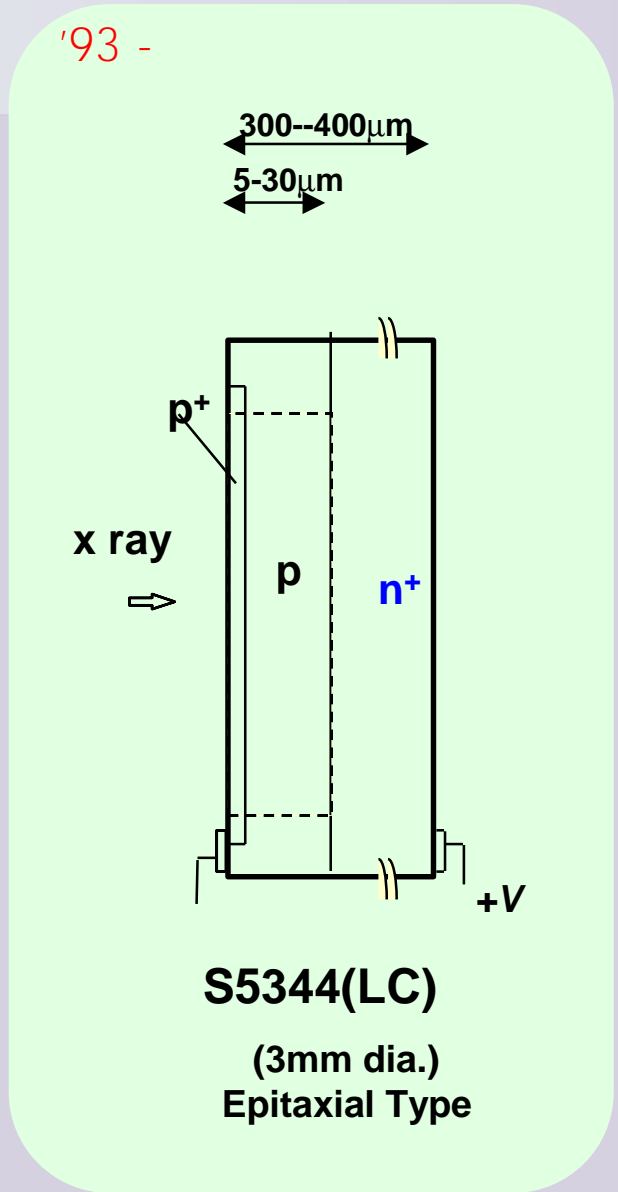
Improvements of HM's APDs



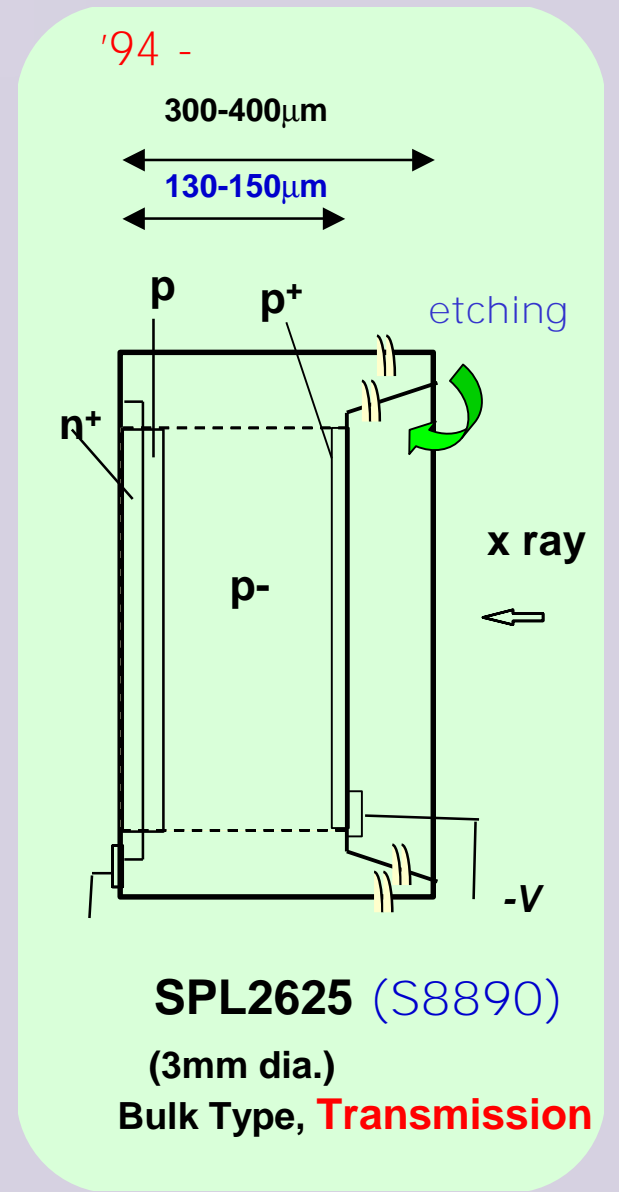
S2384
(3mm dia.)
Epitaxial Type



Time Response



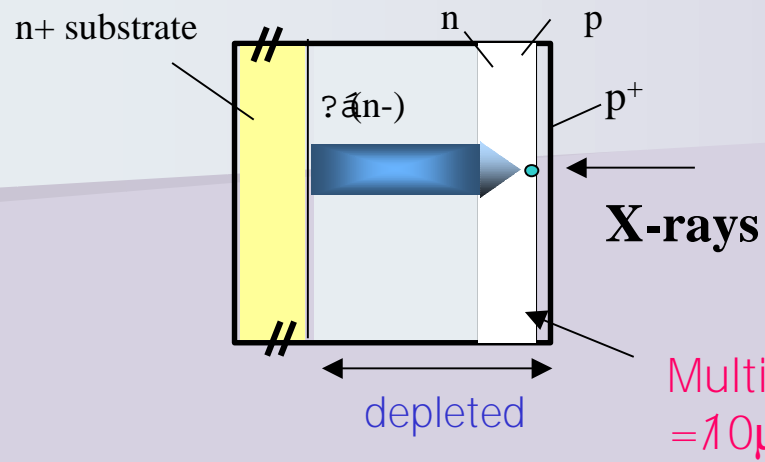
Efficiency



Hamamatsu Si-APDs for NRS (X & γ rays)

Model	Size (mm)	Thickness (μm)	Type
S238X	1-5 dia.	30	Epitaxial Injection: n ⁺ side
S534X (S534X LC)	3,5 dia. (0.5-5 dia.)	10 (20, 30)	Epitaxial Injection: p ⁺ side
S8890 (SPL2625)	0.2-3 dia. (3 dia., 3x5, 5x5)	130-150	Injection: n ⁺ side (Injection: p ⁺ or n ⁺ side)
S8864	0.2-5 dia., 5x5, 10x10	7-10 (45)	Reverse structure (developed for High energy Phys. Exp.)

Reverse structure – “sensitive” only near the surface region

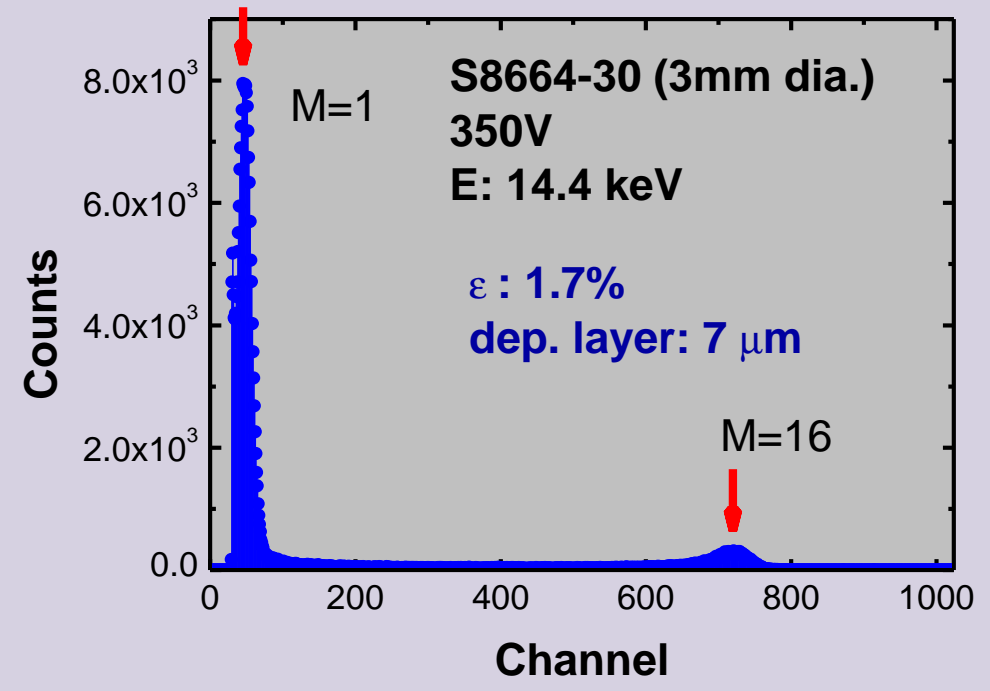


Multiplication = 10 μm

Energy spectrum

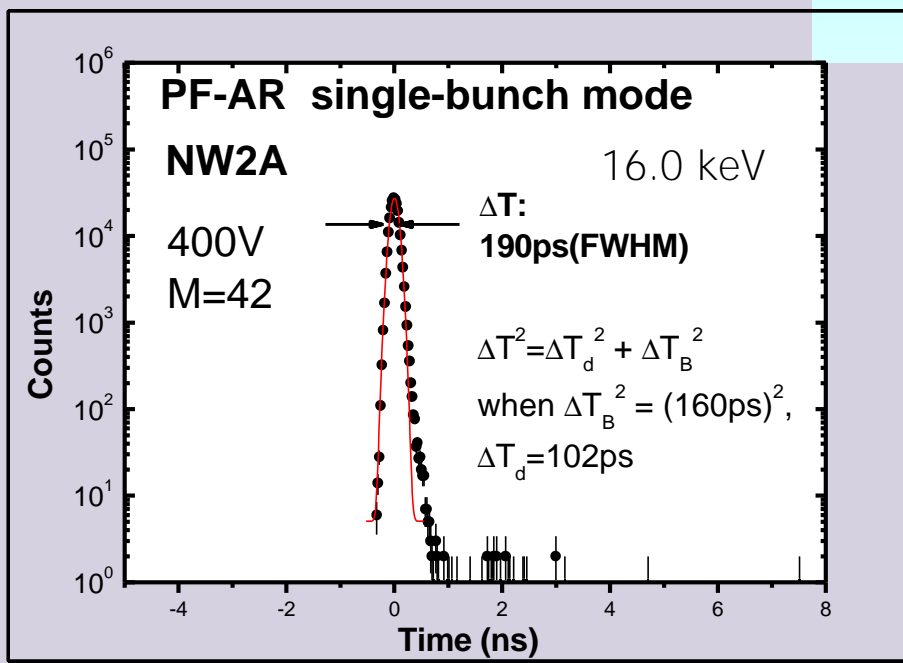
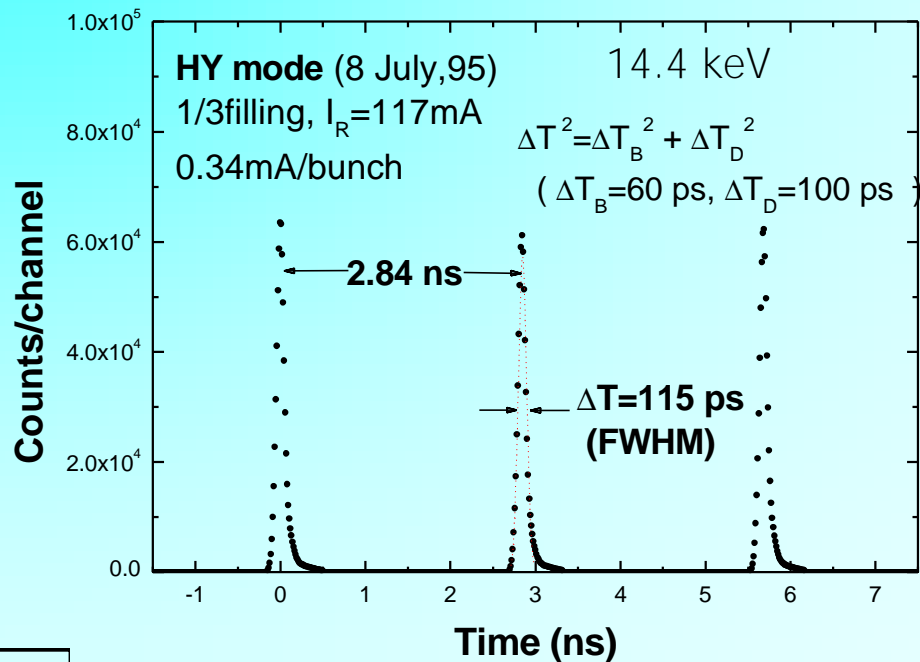
S8664 series

$C_p \sim 20\text{pF}$ (3mm dia.)



Timing

S5343
(1mm dia., 10 μ m)



S8664-30
(3mm dia., 7-10 μ m)

$\Delta T < 100$ ps is possible !

Efficiency and Solid-angle

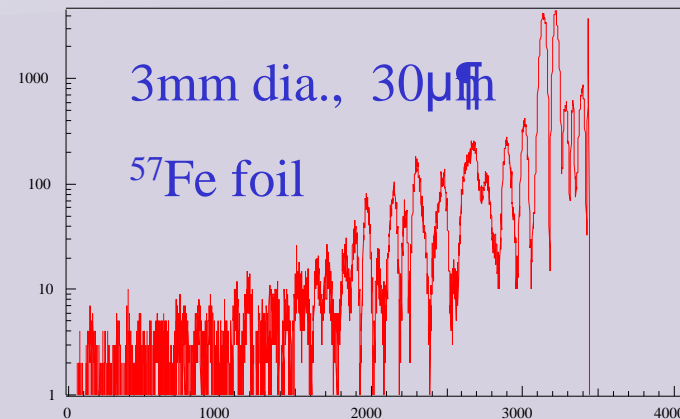
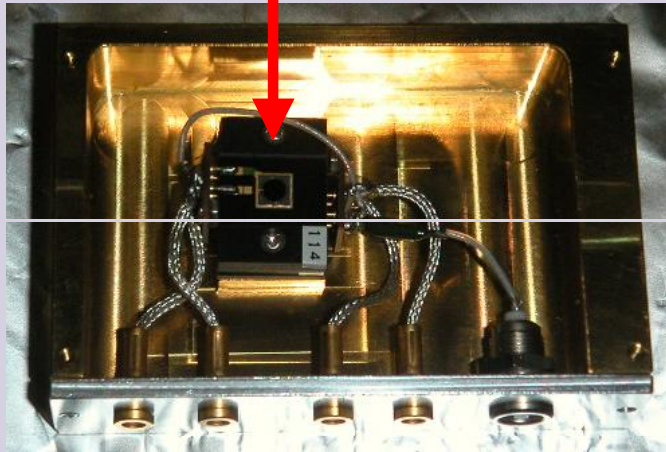
Stack of
Transmission-type
APDs



more efficiency without deficit of a time resolution

Stacking of 4 plates (SPL2625 type)

3mm dia. : 30, 150 μ m
3x5 mm : 150 μ m



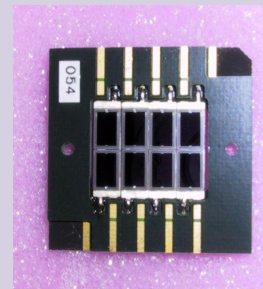
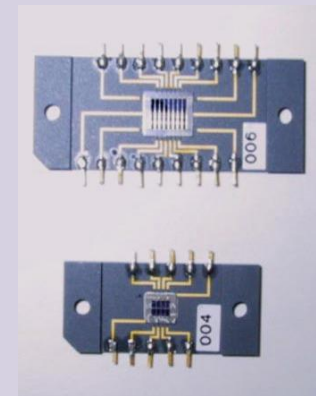
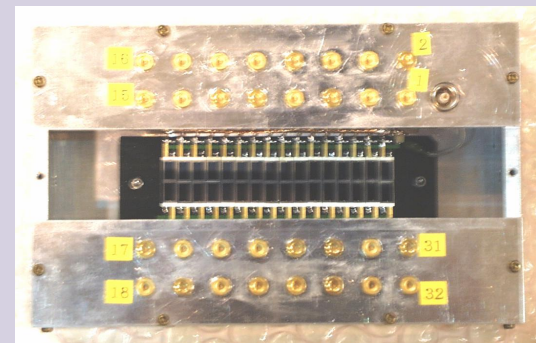
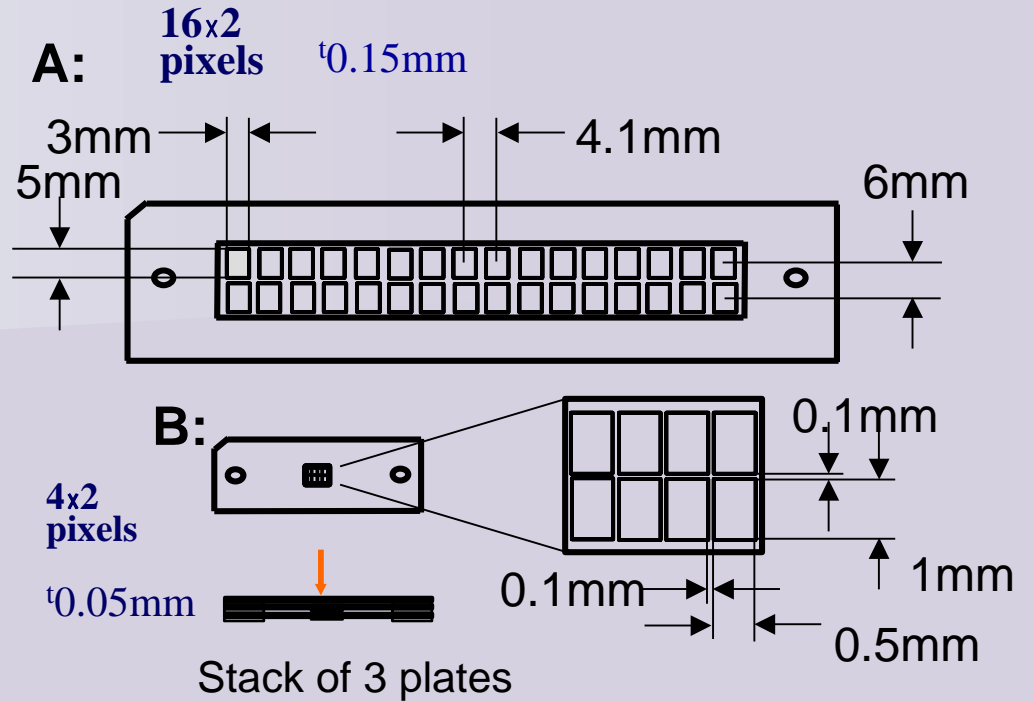
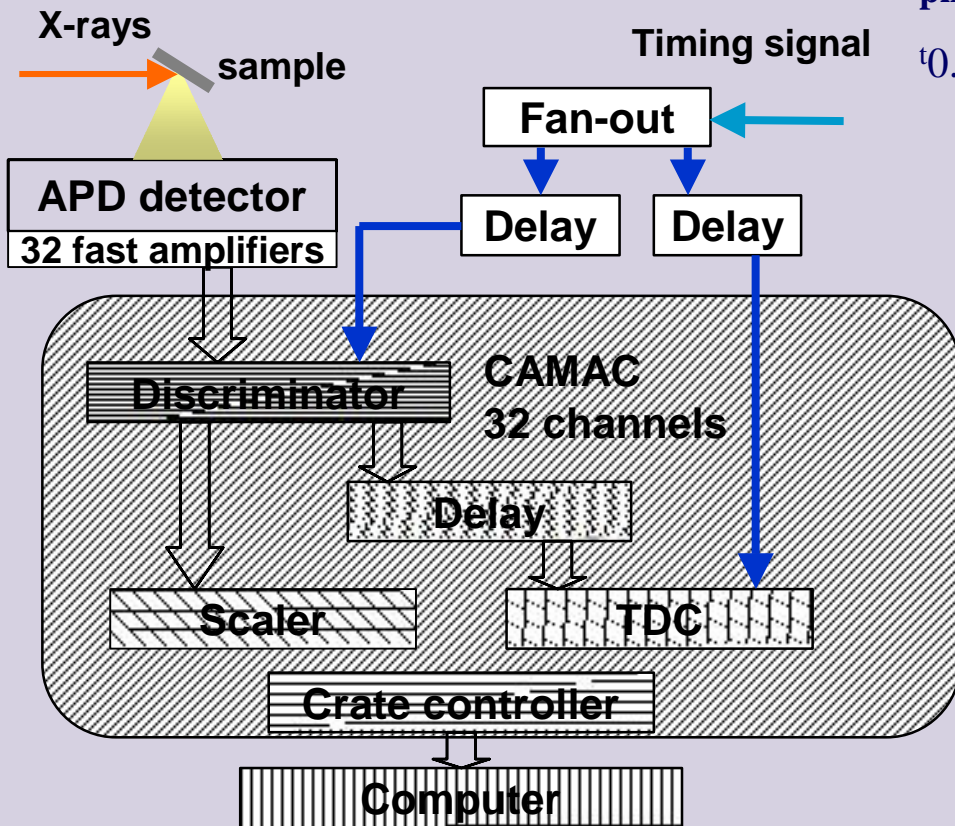
200ns ← 0

á á4-ch ó ó ó ó ó ó ó	
efficiency(14.4keV)	
3mm dia. /30 μ m x x x x x	26%
3mm dia. /150 μ m	78%

Si-APD Array

'97~ : tested some prototypes

The detector system for the APD array (32 ch)

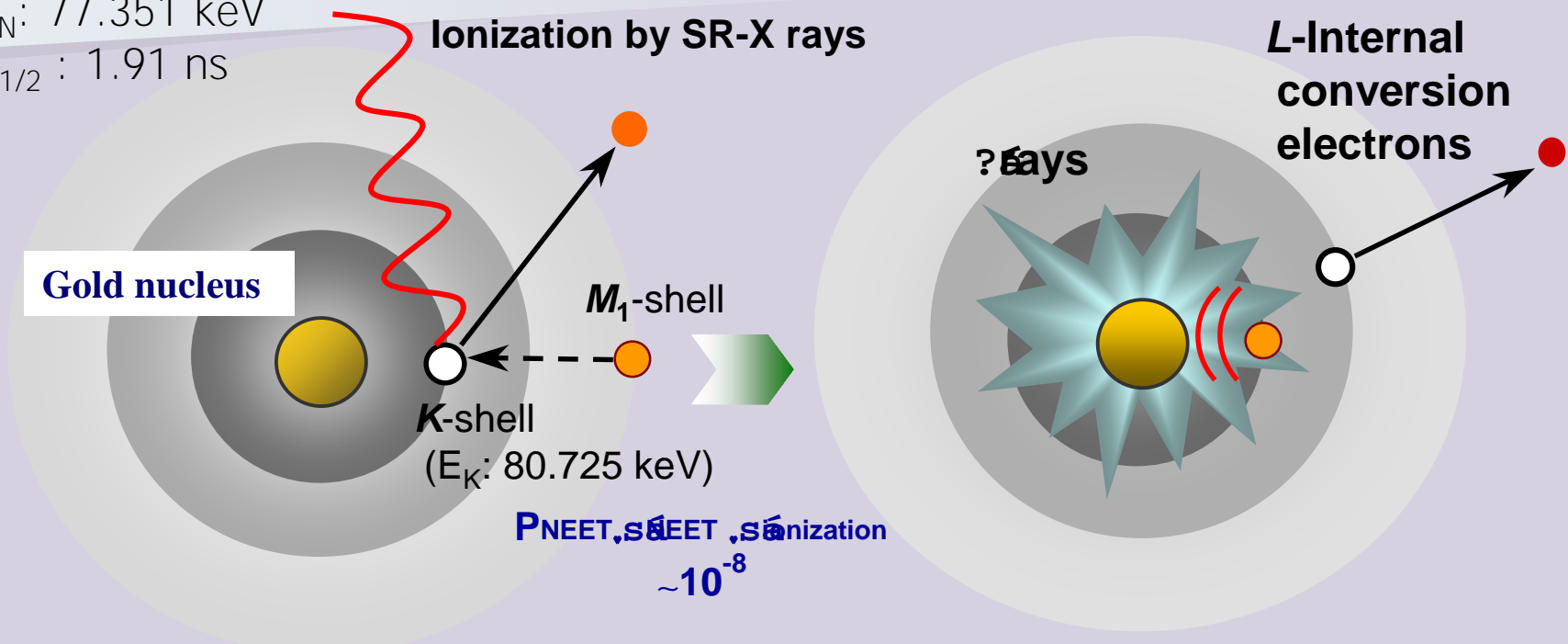


Device's design is depending on requests of an experiment !

3. Nuclear Excitation by Electron Transition (NEET) and Si-AD

Ex. ^{197}Au , Phys.Rev.Lett. 85,1831(2000)

E_N : 77.351 keV
 $T_{1/2}$: 1.91 ns

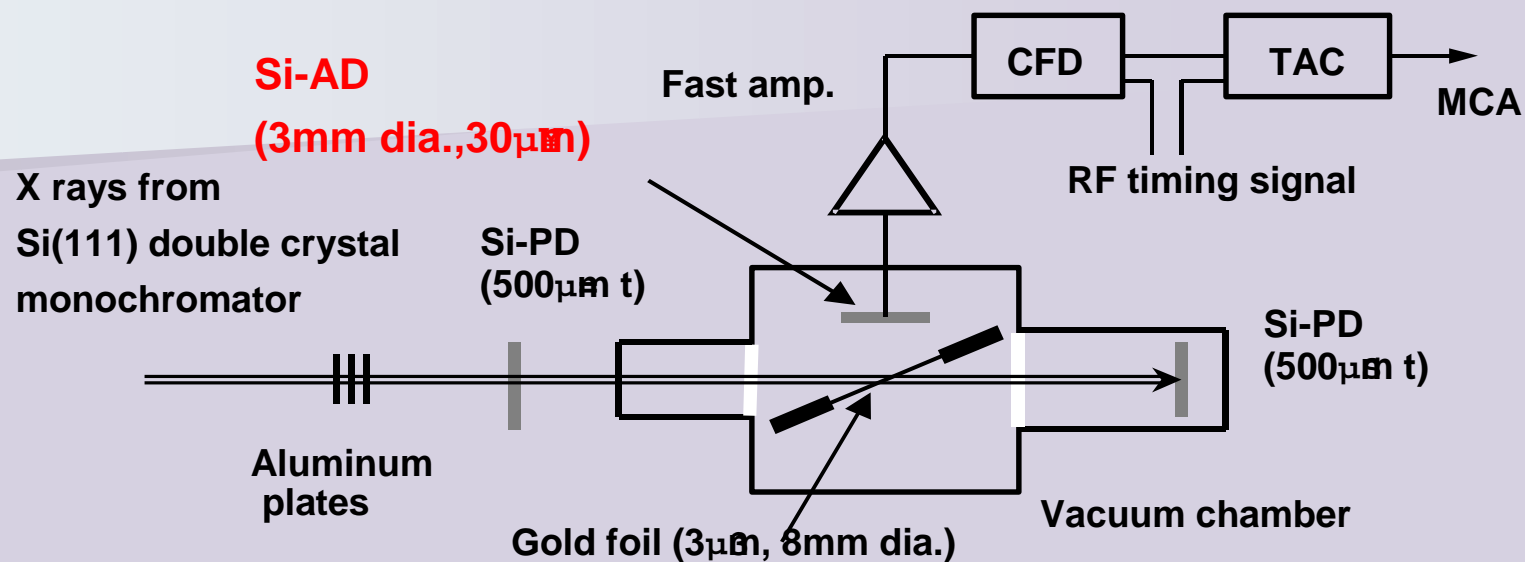


K-holes are made by ionization, and filled by an atomic transition from an outer orbit (M_1).

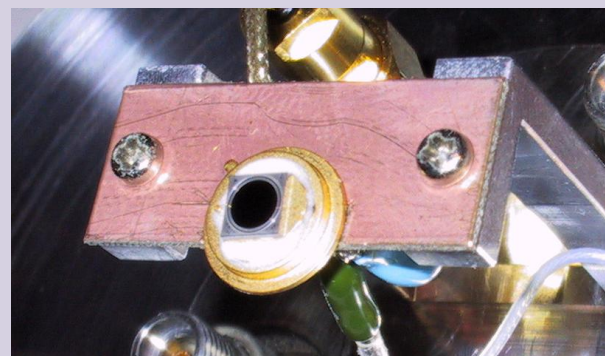
The nucleus is excited, followed by emitting radiation with a lifetime of the excited level.

NEET experiment at SPring-8.BL09XU

A Si avalanche diode was used to detect *L*-Internal conversion electrons.



Detecting Internal conversion electrons



Detection of electrons by Silicon Avalanche Diode

Si-AD : S5344LC, 30 μm thick (L_I conv. $E=63\text{keV}$, $\lambda_e \sim 24\mu\text{m}$)

→ a thin SiO_2 layer : 15-20nm (cf. std.: 130nm)

Charge-up in the insulator & discharge !

⇒ To suppress Discharge :
a groove

SPL3940(Oct.1994)

SPL3941(Nov.1995)

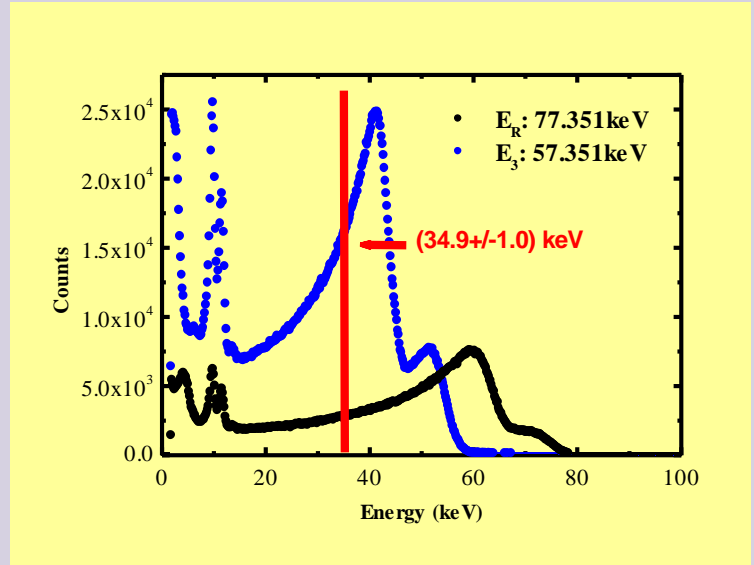


1mm dia. 10 μm^t

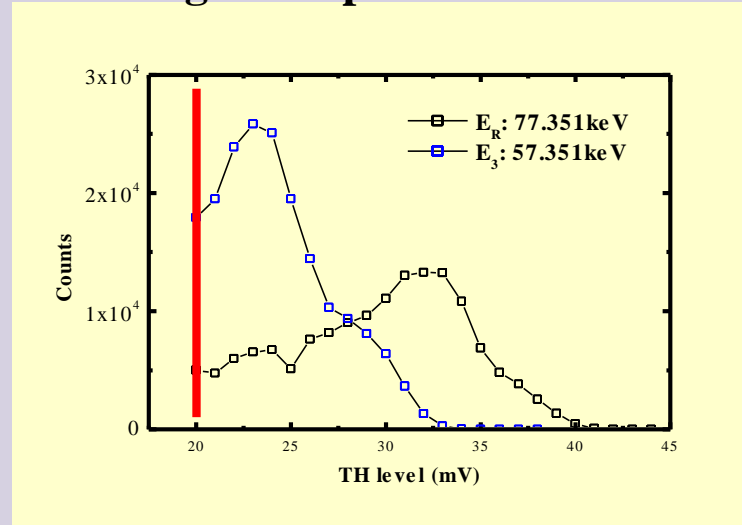


1mm dia. 30 μm^t

(a) Energy spectra

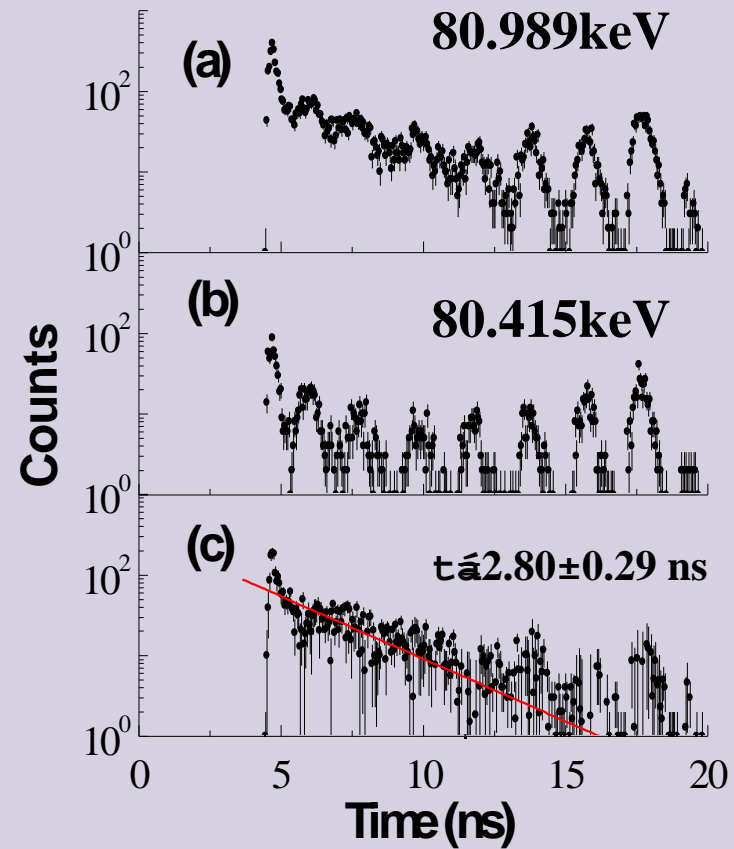
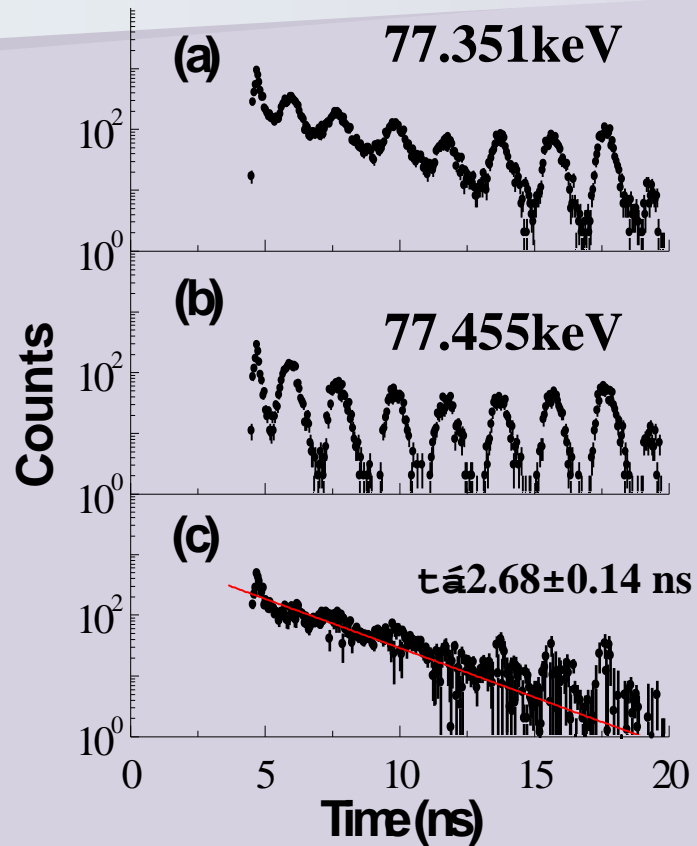


(b) Pulse-height distribution of fast pulses in measuring time spectra



Results in Au-197 Exp.

Time spectra of Nuclear resonant (left) & NEET (right).

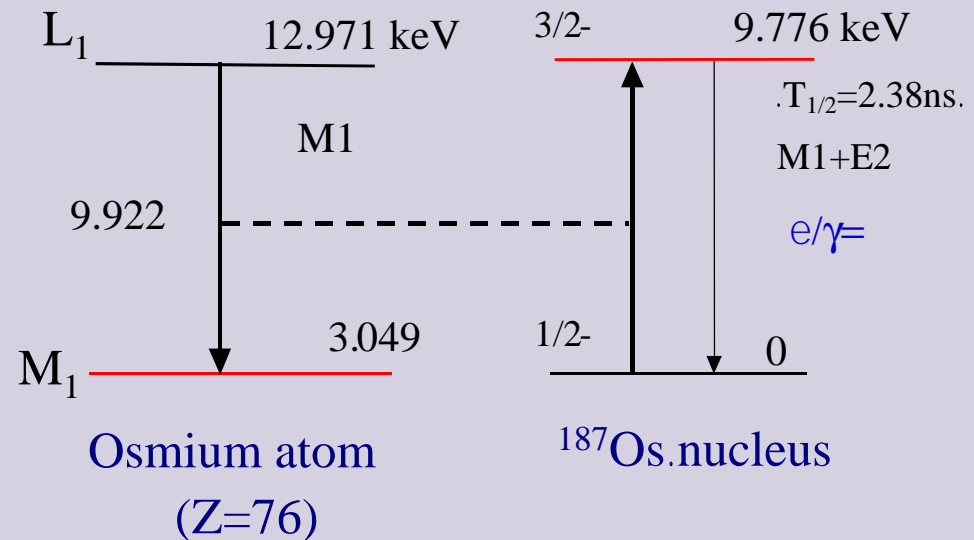


$$T_{1/2} = 1.91 \text{ ns} \text{ ? } \text{ } \text{ } \text{ } 2.76 \text{ ns}$$

$$P_{\text{NEET}} = (5.0 \pm 0.6) \times 10^{-8}$$

	E_{ion} (keV)	E_M (keV)	E_N (keV)	$T_{1/2}$ (ns)	ϵ (keV)	P_{NEET} (cal)
^{197}Au (Z=79) 100%	80.725 (K)	3.425(M ₁)	77.351	1.91	-0.051	3.8×10^{-8}
^{193}Ir (Z=77) 62.7%	76.111 (K)	3.174(M ₁)	73.044	6.09	-0.107	2.0×10^{-9}
^{189}Os (Z=76) 16.1%	73.856 (K)	3.049(M ₁)	69.537	1.62	1.270	1.1×10^{-10}
^{187}Os (Z=76) 1.6%	12.971(L ₁)	3.049(M ₁)	*9.776 (9.746)	2.38	0.146	$1 \times 10^{-8} ?$

PF-AR NW2
& SPring-8 BL09XU



New devices for electron detection

Array : SPL2764

1x6 mm, 3 pixels (1.1-mm pitch), 30- μm depletion layer

To increase efficiency of electrons

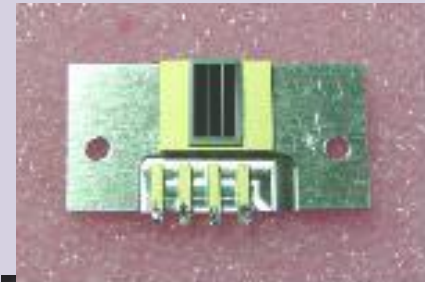
$\Omega \sim 10\%$ (by double-sides setup) cf. 2% for 3mm dia.

Reverse structure : SPL3479 (under development)

A thin ($< 5\text{-}\mu\text{m}$) junction
to reduce the efficiency for elastic X-rays
at detection of low-energy electrons.

For Os-187 exp.,
7-keV Electron: $\lambda_e \sim 0.6 \mu\text{m}$

In a 5- μm layer,
12-keV X-rays: $\epsilon \sim 2\%$
Cf. 30- μm dep. $\epsilon \sim 12\%$

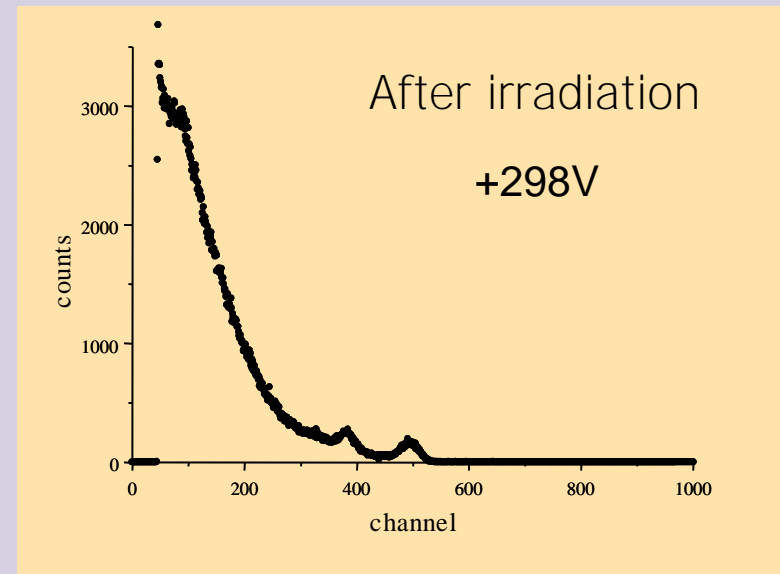
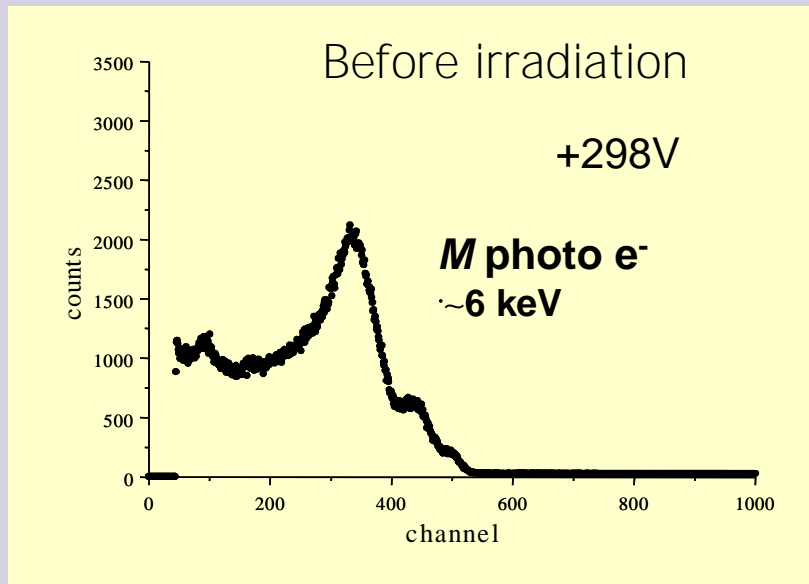


TO-8 mount



A **dead layer** is induced under a surface coating by intense irradiation of electrons. In detection of low-energy electrons ($<10\text{keV}$), this is a serious damage.

ex. 8.41-keV x-rays, Tm film($0.2\mu\text{m}$) evaporated on Mylar, at injection of $>10^{12}$ electrons (photo- e^-),



Due to Passivation of p^+ layer by hydrogen migration (under investigation)

To decrease the damage : a Si_3N_4 layer (15-25nm) is effective ?

4. For Future

In Nuclear excitation experiments by using SR-X rays,

Present

Width of X-ray pulses: .50-200ps.(FWHM)

Half-life of excited levels ($T_{1/2}$).order of nanosecond

...Res.-, ⁴⁰K, .4ns ..29.8keV,

...



. **Shorter Width of X-ray pulses** ..100fs-1ps

... $T_{1/2}$..extended to picosecond region

...ex. Res.-, ¹⁵⁵Gd, .193ps, .60.0keV,

Wider energy region : >30keV

What should we do to improve the detectors ?

To improve the time response,

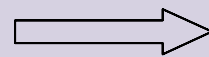
a thin Si-APD is useful

ΔT of several 10-ps will be possible with S8660 or S534X type
But, $\Delta T = \lesssim$ ps is not possible by APD.

To improve the intrinsic efficiency
for a high-energy photon (> 30 keV),

1. Effective Use of Si-APD

Stack or grazing incidence
Detection of Secondary X-rays

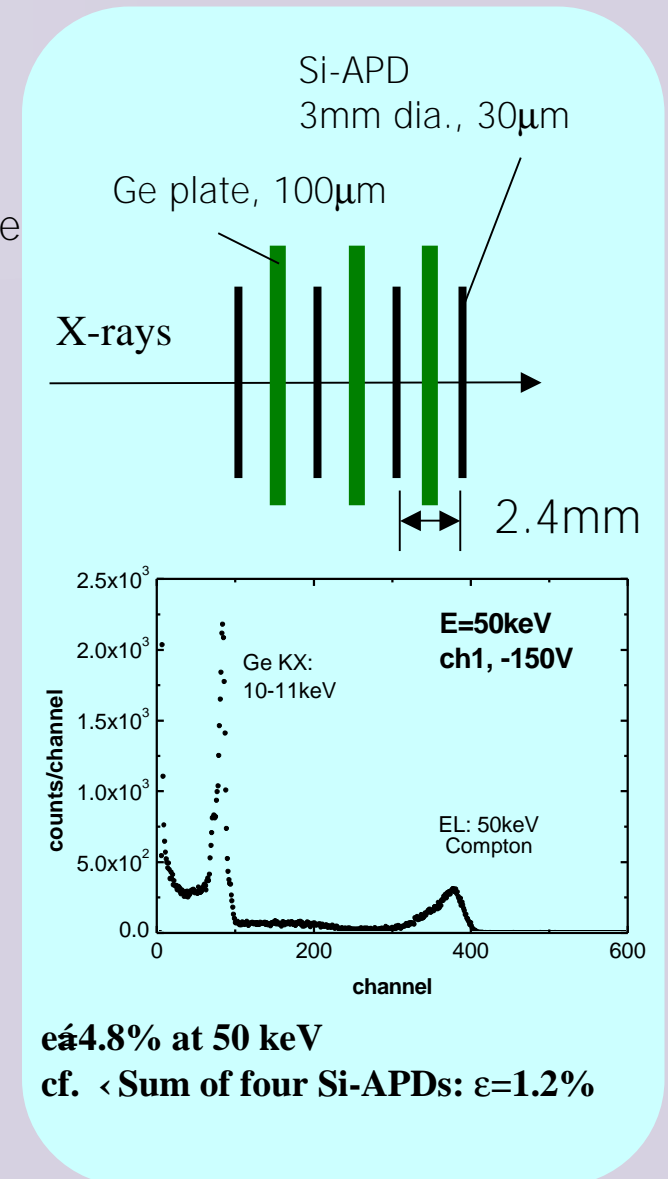


2. A heavier-element APD or PD

APD: GaAs, InGaAs, Ge ? PD: CdTe ?

3. Use of a fast Scintillator

ex. ps-decay emission of free-exciton recombination
in a direct bandgap semiconductor



5. Conclusions

1. Si-APD for NRS

Si-APD devices have been improved for NRS experiments.

Time response: cutting a long “tail” by changing the device structure

Efficiency: transmission-type APDs

2. In NRS or other nuclear excitation experiments,

Si-APDs will still be playing an important role.

faster response : several 10-ps time resolution is possible.

more efficiency at higher energies: stack or grazing incidence

Array devices: tile-arrangement or monolithic device

electron detection: high count-rate with a sub-ns ΔT

Si-APD has a flexibility in size and in structure to be designed.

but expensive ! : a new batch costs \$ 20K-100K.

3. To step up for future, a break-through may be needed in a detector.

An APD detector of Not silicon?

A detector of Not APD?

We need more efforts and more researchers for detector development !